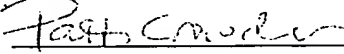




3729

PATENT  
P114-US

<p align="center"><b>CERTIFICATE OF MAILING BY "FIRST CLASS MAIL" 37 C.F.R. §1.8</b></p> <p>I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail on <u>January 30, 2003</u> in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.</p> <p align="center"> Patti Crowder</p>
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#19  
02/12/03

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

<p>In the application of: Mathieu et al. Application No.: 09/527,931 ✓ Filing Date: March 17, 2000 For: Method And Apparatus For Burning-In Semiconductor Devices In Wafer Form</p>	<p>Examiner: R. Chang Group Art Unit: 3919</p>
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**NOTICE OF RELATED PATENT**

Assistant Commissioner for Patents  
Washington, D.C. 20231

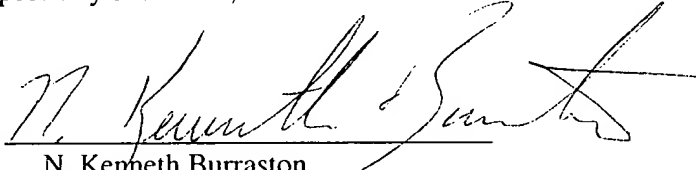
Sir:

Applicants wish to draw the Examiner's attention to the following commonly owned patent (and the art cited therein), whose subject matter may be deemed related to the subject matter of the above-identified application.

US pat. no.: 6,509,751 (P101-US) issued January 21, 2003

Respectfully submitted,

Date: January 30, 2003

By:   
N. Kenneth Burraston  
Reg. No. 39,923

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